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App. No. 10/501,744
Amendment dated November 30, 2005
Reply to Office action of August 31, 2005

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the present application.

Listing of Claims:

Claim 1 (currently amended): For semiconductor manufacturing equipment, a ceramic susceptor comprising:

a ceramic substrate deployed on a substantially cylindrical shaft;

a resistive heating element formed either superficially or interiorly in said ceramic substrate; and

a concavity molded in a wafer-carrying face defined on a surface of said ceramic substrate through which said resistive heating element issues heat when the susceptor performs a heating operation, said concavity being ~~0.001 to 0.7 mm/300 mm~~ 0.001 to 0.7 mm per 300 mm length along the wafer-carrying face in negative arched contour when the susceptor is not heating; and

the shaft disposed to warp the substrate in a controlled manner, thereby causing at least a portion of said concavity of the wafer carrying face.

Claim 2 (original): A ceramic susceptor as set forth in claim 1, wherein the ceramic substrate is made of at least one ceramic selected from aluminum nitride, silicon nitride, aluminum oxynitride, and silicon carbide.

Claim 3 (original): A ceramic susceptor as set forth in claim 1, wherein the resistive heating element is made from at least one metal selected from tungsten, molybdenum, platinum, palladium, silver, nickel, and chrome.

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Claim 4 (original): A ceramic susceptor as set forth in claim 1, further comprising a plasma electrode disposed either in the surface or in the interior of said ceramic substrate.

Claim 5 (original): A ceramic susceptor as set forth in claim 2, wherein the resistive heating element is made from at least one metal selected from tungsten, molybdenum, platinum, palladium, silver, nickel, and chrome.

Claim 6 (original): A ceramic susceptor as set forth in claim 2, further comprising a plasma electrode disposed either in the surface or in the interior of said ceramic substrate.

Claim 7 (original): A ceramic susceptor as set forth in claim 3, further comprising a plasma electrode disposed either in the surface or in the interior of said ceramic substrate.

Claim 8 (original): A ceramic susceptor as set forth in claim 5, further comprising a plasma electrode disposed either in the surface or in the interior of said ceramic substrate.

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